

APPENDIX A
"CLEAN" VERSION OF EACH PARAGRAPH/SECTION/CLAIM
37 C.F.R. § 1.121(b)(ii) AND (c)(i)

CLAIMS (with indication of amended or new):

1. (AMENDED) A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

A1 a transport robot successively transporting said substrate between said plurality of processing parts along a prescribed procedure; and

a plurality of inspection parts, performing substrate inspections of different contents respectively, provided in said substrate processing apparatus, wherein

said transport robot transports each of part or all of a set of plural substrates to be subjected to the same processing to a single inspection part selected from said plurality of inspection parts, thereby transporting at least one and less than all of said set of plural substrates to each of said plurality of inspection parts.

4. (AMENDED) The substrata processing apparatus according to claim 1, wherein

A2 a transport path is formed along said procedure, and

each of said plurality of inspection parts is arranged on an intermediate position in said transport path responsive to the inspection contents thereof.

9. (AMENDED) A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

A3 a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure;

an inspection part capable of performing an inspection including a plurality of inspection contents on said substrate; and

a procedure setting part capable of incorporating substrate transportation to said inspection part into an arbitrary order position in said procedure, wherein

said transport part transports each part or all of a set of plural substrates to be subjected to the same processing to said inspection part where an inspection selected from said plurality of inspection contents is performed on at least one and less than all of said set of plural substrates in said inspection part.

A3
10. (AMENDED) The substrate processing apparatus according to claim 9, wherein said plurality of inspection contents of said inspection part include resist film thickness measuring, pattern line width measuring and pattern overlay measuring.

A4
12. (AMENDED) A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure;

a plurality of inspection parts performing prescribed inspections on said substrate;

a procedure setting part capable of individually incorporating substrate transportation to said plurality of inspection parts into an arbitrary order position in said procedure; and

a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part, wherein

said procedure setting part sets transport of each of part or all of a set of plural substrates to be subjected to the same processing to a single inspection part selected from said plurality of inspection parts, so that at least one and less than all of said set of plural substrates are transported to each of said plurality of inspection parts.

A5
17. (AMENDED) A substrate processing system for performing prescribed processing on a substrate comprising:

a) a substrate processing apparatus comprising:

a-1) a plurality of processing parts processing said substrate,

a-2) a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure, and

a-3) a plurality of inspection parts performing a prescribed inspection on said substrate;

b) a procedure setting part capable of incorporating substrate transportation to said plurality of inspection parts into an arbitrary order position in said procedure; and

c) a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part, wherein said procedure setting part sets transport of each of part or all of a set of plural substrates to be subjected to the same processing to a single inspection part selected from said plurality of inspection parts, so that at least one and less than all of said set of plural substrates are transported to each of said plurality of inspection parts.

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18. (AMENDED) The substrate processing system according to claim 17, wherein each of said plurality of inspection parts is any of a thickness measuring part measuring the thickness of a resist film, a line width measuring part measuring the line width of a pattern, an overlay measuring part measuring overlay of said pattern and a macro defect inspection part.

19. (AMENDED) The substrate processing system according to claim 17, wherein any of said plurality of inspection parts is capable of performing resist film thickness measurement, pattern line width measurement and pattern overlay measurement.

AP

20. (NEW) A substrate processing system performing prescribed processing on a substrate, comprising:

a) a substrate processing apparatus comprising:

a-1) a plurality of processing parts processing said substrate;

a-2) a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure, and

a-3) an inspection part capable of performing a prescribed inspection including a plurality of inspection contents on said substrate; and

b) a procedure setting part capable of incorporating substrate transportation to said inspection part into an arbitrary order position in said procedure, wherein said transport part transports each of part or all of a set of plural substrates to be subjected to the same processing to said inspection part where an inspection selected from said plurality of inspection contents of said inspection part is performed, so that each of said plurality of inspection contents is performed on at least one and less than all of said set of plural substrates in said inspection part.

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21. (NEW) The substrate processing system according to claim 20, wherein said plurality of inspection contents of said inspection part include resist film thickness measuring, pattern line width measuring and pattern overlay measuring.

APPENDIX B
VERSION WITH MARKINGS TO SHOW CHANGES MADE
37 C.F.R. § 1.121(b)(iii) AND (c)(ii)

CLAIMS:

1. (AMENDED) A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

 a transport robot successively transporting said substrate between said plurality of processing parts along a prescribed procedure; and

 a plurality of inspection parts, performing substrate inspections of different contents respectively, provided in said substrate processing apparatus, wherein

said transport robot transports each of part or all of a set of plural substrates to be subjected to the same processing to a single inspection part selected from said plurality of inspection parts, thereby transporting at least one and less than all of said set of plural substrates to each of said plurality of inspection parts.

4. (AMENDED) The substrata processing apparatus according to claim [3] 1, wherein

 a transport path is formed along said procedure, and

 each of said plurality of inspection parts is arranged on an intermediate position in said transport path responsive to the inspection contents thereof.

9. (AMENDED) A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

 a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure;

 an inspection part capable of performing [a prescribed inspection] an inspection including a plurality of inspection contents on said substrate; and

a procedure setting part capable of incorporating substrate transportation to said inspection part into an arbitrary order position in said procedure[; and], wherein

[a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part.]

said transport part transports each part or all of a set of plural substrates to be subjected to the same processing to said inspection part where an inspection selected from said plurality of inspection contents is performed on at least one and less than all of said set of plural substrates in said inspection part.

10. (AMENDED) The substrate processing apparatus according to claim 9, wherein [said procedure setting part is capable of setting said procedure every said substrate]
said plurality of inspection contents of said inspection part include resist film thickness measuring, pattern line width measuring and pattern overlay measuring.

12. (AMENDED) A substrate processing apparatus successively transporting a substrate between a plurality of processing parts thereby performing prescribed processing on said substrate, comprising:

a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure;

a plurality of inspection parts performing prescribed inspections on said substrate;

a procedure setting part capable of individually incorporating substrate transportation to said plurality of inspection parts into an arbitrary order position in said procedure; and

a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part, wherein

said procedure setting part sets transport of each of part or all of a set of plural substrates to be subjected to the same processing to a single inspection part selected from said plurality of inspection parts, so that at least one and less than all of said set of plural substrates are transported to each of said plurality of inspection parts.

17. (AMENDED) A substrate processing system for performing prescribed processing on a substrate comprising:

- a) a substrate processing apparatus comprising:
 - a-1) a plurality of processing parts processing said substrate,
 - a-2) a transport part successively transporting said substrate between said plurality of processing parts along a prescribed procedure, and
 - a-3) [an inspection part] a plurality of inspection parts performing a prescribed inspection on said substrate;
- b) a procedure setting part capable of incorporating substrate transportation to said plurality of inspection [part] parts into an arbitrary order position in said procedure; and
- c) a transportation control part controlling said transport part to successively transport said substrate along said procedure set by said procedure setting part, wherein
said procedure setting part sets transport of each of part or all of a set of plural substrates to be subjected to the same processing to a single inspection part selected from said plurality of inspection parts, so that at least one and less than all of said set of plural substrates are transported to each of said plurality of inspection parts.

18. (AMENDED) The substrate processing system according to claim 17, wherein [said procedure setting part is capable of setting said procedure every said substrate]
each of said plurality of inspection parts is any of a thickness measuring part measuring the thickness of a resist film, a line width measuring part measuring the line width of a pattern, an overlay measuring part measuring overlay of said pattern and a macro defect inspection part.

19. (AMENDED) The substrate processing system according to claim 17, wherein [said procedure setting part is capable of setting a procedure every set of a prescribed number of said substrates]
any of said plurality of inspection parts is capable of performing resist film thickness measurement, pattern line width measurement and pattern overlay measurement.